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Dual Nanowire Silicon MOSFET With Silicon Bridge and TaN Gate

A. L. Theng, W. L. Goh, Member, IEEE, G. Q. Lo, Senior Member, IEEE, L. Chan, and C. M. Ng

Abstract—This paper demonstrates a high performance silicon nanowire mosfet built on silicon-on-insulator (SOI) platform. Stress-limiting oxidation technique was exploited for dual nanowire channel formation. To further improve the performance of the device, TaN metal gate is used instead of the conventional polysilicon gate. The thin silicon bridge between the two nanowires provides a small boost in the drive current, without degrading the short channel performance. The novel structures are able to achieve excellent electrical performances, high drive current of 927 $\mu$A/µm for p-channel and 554 $\mu$A/µm for n-channel, near ideal subthreshold slope (SS), and low drain-induced barrier lowering (DIBL).

Index Terms—Silicon nanowire transistor, silicon-on-insulator (SOI) technology.

I. INTRODUCTION

TRANISTOR scaling has led to the exploration of various nonclassical devices for the delivery of high performance devices. Double-gate FinFET [1], tri-gate [2], gate-all-around (GAA) [3], and the nanowire FinFETs [4]–[6] are some well-known structures reported. These devices are innate with good suppression of short-channel effects (SCEs), high drive current and excellent $I_{on}/I_{off}$ ratio. Silicon nanowire transistors have been attracting the attention of researchers mainly for their improvement in the transport property [7] and their compatibility with CMOS process [5], [6]. The published results on polysilicon gate nanowire transistors [5], [6] have been well covered. Nevertheless, the performance of nanowire transistors can be further enhanced using high-$\Delta$ dielectric and metal gate [4].

In this paper, we present the dual nanowire field effect transistor (DNWFET) devices that are fabricated using HfO$_2$ and TaN as the gate dielectric and gate material, respectively. TaN metal gate is engaged to improve the work function of the nanowire transistors. Not only a suitable threshold voltage ($V_T$) can be attained, but also the leakage current is reduced. The top and bottom nanowires are bridged by a thin silicon layer to enhance the drive current without much degradation in the short channel performance. The nanowire channel is wrapped around by a TaN gate to provide optimum electrostatic control.

II. FABRICATION OF NANOWIRE MOSFET

The SOI wafers with 70 nm p-type ($\sim 10^{15}/cm^3$) top silicon and 150 nm buried oxide (BOX) are used as starting materials. Lithography and resist trimming are performed to achieve a fin width of around 50 nm. The wafers are etched and sent for dry oxidation at 875 $^\circ$C for 5 h. With well-controlled self-limiting oxidation process, dual nanowire channels that are connected by a thin silicon bridge can be established. The oxidation process makes use of the different oxidation rates of the various silicon planes to form the two nanowires. The sides of the fins that are at 1 1 0 plane oxidize two times faster than the top of the fin (at 1 0 0 plane). With the close proximity of the two nanowires, and the precisely controlled oxidation parameters and timings, a thin silicon bridge can be formed. The oxidized structure is later released with a dilute hydrofluoric acid (DHF) dip. The hydrofluoric acid (HF) dip also undercuts the BOX layer to facilitate the development of the wrap around gate.

Fig. 1(a) shows the dual nanowire upon oxide removal. A high quality gate oxide of 20 Å is then grown, followed by a 30 Å HfO$_2$ deposition to complete the gate dielectric stack. The 800 Å of TaN that wraps around the nanowire channel is then deposited using physical vapor deposition (PVD), for improving the electrostatic control of the device [see Fig. 1(b)]. The TaN gate electrode is patterned with a triple-layered hardmask (oxide–nitride–oxide) process. Two hardmask etching steps with additional wet processes in between are required to provide a clean TaN etch [see Fig. 1(c)]. BF$_2$ and As of dose $4 \times 10^{15}$ cm$^{-2}$ with 10 and 20 keV energy for the $p$- and $n$-DNWFETs are engaged for the implantation step. To form the source and drain, the device is given a short 10 s source/drain (S/D) activation anneal prior to contact formation and metallization for the device. The process finally ended with a sintering at 430 $^\circ$C. Fig. 1(d) is the TEM cross section of a 5-nm diameter dual nanowire channel with a 1 nm silicon bridge, surrounded by gate dielectric and TaN gate. An overview of the processing steps is listed in Fig. 1(e). Fig. 2 provides the schematic views of the DNWFET structure.

III. RESULTS AND DISCUSSIONS

The $I_d$ vs $V_d$ and $I_d$ vs $V_g$ characteristics of the 350-nm long nanowire MOSFET devices are given in Fig. 3. At an operating
Fig. 1. SEM pictures of the device after various processing steps. (a) Nanowires released after DHF dip. (b) TaN deposition causing deformation of nanowire channel. (c) TaN gate etch. (d) TEM image of dual 5-nm diameter nanowire with 1 nm silicon bridge wrapped around by TaN gate. (e) Summary of processing steps for DNWFET.

Fig. 2. Several views of the dual nanowire device. (a) 3-D view. (b) Cross-sectional view across channel at x–z plane. (c) Cross-sectional view on y–z plane. (d) 3-D view of the channel region.

Voltage of 1.5 V, the p-DNWFET exhibits a drive current of 927 µA/µm, while the n-DNWFET achieving 554 µA/µm. The p- and n-DNWFET exhibits comparable leakage currents of 0.9 and 1.8 nA/µm, respectively, both taken at zero gate voltage. All currents are normalized with the nanowire diameters and silicon bridge width. This gives a spread of $I_{ON}/I_{OFF}$ ratio between $10^5$ and $10^6$. The high drive current is attributed to the volume inversions of the two silicon nanowires. Strain generated from the thermal oxidation process [8] and stress from the TaN deposition process provide mobility enhancement in the devices. The thin 1 nm silicon bridge is believed to contribute only a small current boost. The higher $I_{ON}$ current observed in p-DNWFET as compared to that in n-DNWFET is mainly attributed to the difference in $V_T$, the higher total on resistance of n-DNWFET as compared to that of p-DNWFET, and also variation in the effective carrier mass between the two. These observations are also reported in [9]. Note that for DNWFET devices, this difference in $I_{ON}$ current is made more severe by the large difference in the two $V_T$. Measurements show the p-DNWFET achieved a $V_T$ of $-0.29$ V, while the n-DNWFET has a high $V_T$ of...
Fig. 3. (a) $I_d$ vs $V_g$ plots. (b) $I_d$ vs $V_d$ plot of 350 nm dual nanowire MOSFET devices. Note that the currents have each been normalized to the diameters of the nanowires.

0.56 V. Fixing an operating voltage of 1.5 V would indicate a lower overdrive ($V_g-V_T$) for $n$-DNWFET, and hence, yielding a lower drive current.

We should also note that after the gate etch, the expose portions of the nanowire [see Fig. 2(a) and (b)] is subjected to high dose S/D implantation. This may lead to amorphization of the exposed portions of the nanowire.

Without a template for subsequent recrystallization via solid phase epitaxy, the expose portions of the nanowire is unlikely to recrystallize after the S/D activation anneal. Thanks to the used of boron spices in $p$-DWNFET, which have a higher threshold for amorphization, the expose nanowire portions of the $p$-DWNFET are able to remain crystalline. This results in a higher relative total resistance in $n$-DNWFET than $p$-DNWFET. The lower effective mass of hole as compared to electron of the [1 1 0] direction [9] shows that hole mobility is enhanced.

The wrap-around gate electrode provides a shield to block the drain field, yielding good immunity to the short channel

Fig. 4. $G_m$ plot of 500 nm nanowire devices, with TaN gate device having higher transconductance in comparison to polysilicon device.

Fig. 5. $I_d$ vs $V_g$ graph of polysilicon and TaN gate devices. (a) For NMOS. (b) For PMOS. The implementation of TaN gate shift the plot to the right for NMOS and to the left for PMOS, therefore reducing the OFF-state leakage current, measure at $V_g = 0$.
effects (SCEs). The immunity is reflected in the 65 mV/dec subthreshold slope (SS) and 25 mV/V drain-induced barrier lowering (DIBL) achieved by the PMOS. The NMOS also shows low SS of 66 mV/dec and DIBL of 28 mV/dec. Both the $I_d$ against $V_g$ characteristics of $n$- and $p$-DNWFET are presented earlier in Fig. 3(a).

The midgap TaN gate elevates the $V_T$ to solve the low $V_T$ and high off-state leakage issues seen in polysilicon gate nanowire devices. The elevation of the $V_T$ shifts the PMOS $I_d$ vs $V_g$ curve to the left and NMOS curve to the right, as indicate in Fig. 5(a) and (b). This shift allows the TaN gate device to obtain lower leakages for as much as one order of magnitude as compared to the polysilicon gate device while maintaining high drive current. Although the use of TaN metal gate further increases the $V_T$ of the $n$-DNWFET, this issue can be moderated with a $V_T$ adjustment implant or an $n$-type SOI substrate.

The $G_m$ as a function of the $V_g$ plot of Fig. 4 illustrates the fast response of the transconductance to gate voltage. The transconductance saturates after peaking, and this indicates that these devices are enjoying low field mobility even at high gate voltages. This is attributed to the cylindrical channel morphology [10] and the undoped channel. The DNWFET devices are also immune to the substrate bias, whereby the $V_T$ remains constant when the substrate bias is swept from $-6$ to $6$ V for both the $n$- and $p$-DNWFET. This immunity is further verified with the reference planar SOI devices that are built on the same wafer. The $V_T$ of the reference devices change with substrate bias swept from positive to negative for PMOS and vice versa for NMOS. The substrate bias immunity is a result of the wrapped around gate shielding the channel from unwanted signals. This is illustrated in Fig. 6.

IV. CONCLUSION

We have successfully fabricated TaN gate DNWFET structures. A high drive current is achieved along with excellent SS and DIBL. The $p$-DNWFET surpassed the performance of the $n$-DNWFET due to the higher total resistance of $n$-DNWFET and the lower effective hole mass. The TaN gate is clearly able to improve the gate work function to attain a higher $V_T$, thereby achieving a lower leakage current.

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REFERENCES


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G. Q. Lo, photograph and biography not available at the time publication.

C. M. Ng, photograph and biography not available at the time publication.